X-Ray Diffraction as a key to the Structure of Materials Interpretation of scattering patterns in real and reciprocal space



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#### OUTLINE

1 "Internal" structure of materials – macroscopic characteristics: importance of experimental physics to understand fundamental properties

The dilemma of x-ray optics

- 2 X-rays in structural analysis: diffraction as a sensing parameter for interatomic distances
- 3 Introduction to diffraction and reciprocal space

4 Limits of reciprocal space

5 Getting the most out of real and reciprocal space



#### STRUCTURE AND PROPERTIES: HOW CAN WE KNOW AND WHAT DO WE KNOW?



Mechanical properties

**Optical properties** 

**Electrical properties** 



#### **STRUCUTRE FUNCTION RELATIONSHIP**







Novoselov & Geim Nobel Price 2010:

Using scotch tape to lift of one

atomic layer of *Graphene,* With outstanding mechanical

#### and electrical properties



2010: single layers of  $MoS_2$  turn out to have outstanding electronic properties.



#### **ATOMIC STRUCTURE STUDIED WITH X-RAYS**

TENSKI

Atomic distances typically 0.1 nm (1 Å)



Light λ~500nm

Resolution  $\Delta \mathbf{x}$  of a light microscope:  $\underline{\Delta \mathbf{x}} = 1.22^* \lambda / 2NA \sim 0.6^* \underline{\lambda} / (\mathbf{n}^* \mathbf{sin} \alpha)$ 



High resolution means small wavelengths and large apertures (large collection angles)



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## **X-RAY OPTICS: THE DILEMMA OF REFRACTION**

interaction of electromagnetic waves (light!) and matter (~electron clouds) The refractive index is expressed as n=1- $\delta$ +i $\beta$ =  $\sqrt{\epsilon_{\mu}} \approx \sqrt{\epsilon} = \sqrt{\epsilon_{0}(1+\chi)}$ (n  $\approx \sqrt{1+\chi}$ )  $\chi$ =polarizability

The polarizability  $\chi$  describes the polarization P as a function of a field E: P~ $\chi$ E; in the mechanical equivalent, 1/ $\chi$  is similar to a spring constant

$$\rho_m \ddot{s}(t) + Bs(t) = \rho_e E(t)$$

Inertia Spring constant driving force

Driven oscillator equivalent to simple mechanical model



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We replace s(t) by the Polarization  $P(t)=\rho_e s$ 

Damping factor (friction): \$\phi\$ (we ignore the origin)

 $\ddot{P}(t) + \omega_0^2 P(t) + \phi \dot{P}(t) = \frac{\rho_e^2}{2} E(t)$ 

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#### SOLUTION OF "EQUATION OF MOTION"

With P~χ

What else can we interpret from the mechanical equivalent? Amplitude Resonance  $X_0 \cong P \propto \frac{\omega_0^2}{\sqrt{(\omega_0^2 - \omega^2)^2 + \phi^2 \omega^2}}$ 3.5 0 2.5 X<sub>0</sub> / X<sub>0</sub> Amplitude [m] **For**  $\omega << \omega_0$ : P=const. (does Phase [deg hardly vary with  $\omega$ ) eyeglasses work for all 1.5 colours, In this regime, refraction is almost achromatic 0.5 **For**  $\omega >> \omega_0$ : P~1/ $\omega^2$ , thus P-> 0 -180 **Refraction in the x-ray regime is** 0 0.05 0.1 0.15 0.2 0.25 0.3 Frequency [Hz] very weak and highly chromatic!!, f\_= 0.15915494327376 Hz Q = 3.3333333333333333

n≈0.99999

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 $\approx \sqrt{1+\chi}$ 

 $\ddot{P}(t) + \omega_0^2 P(t) + \phi \dot{P}(t) = \frac{\rho_e^2}{2} E(t)$ 

 $\rho_m$ 

#### Lens surfaces must be paraboloids of rotation



parameters for Be lenses:

 $R = 50 \text{ to } 1500 \mu \text{m}$ 

 $2R_0 = 0.45$  to 2.5mm

d below 30µm

To achieve reasonable refraction, many of such lenses need to be put in series.

The useful aperture is generally absorption limited And of the order of 100  $\mu$ m for 100 mm focal distance.

-> NA~10<sup>-3</sup> (around 1 in the visible)

Resolution  $\Delta x = 1.22^{+}\lambda/2NA \sim 0.6^{+}\lambda/(n^{+}sin\alpha)$ 

parabolic profile: no spherical aberration
 focusing in full plane
 => excellent imaging optics

Slide: A. Snigirev

From visible to x-rays, we win a factor of 10 000 in  $\lambda$  and loose a factor of 1000 in NA



#### **DIFFRACTION AND RECIPROCAL SPACE**



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#### **DIFFRACTION FROM A PERIODIC GRATING**



Angular distance of the peaks<->determines distances of the slits (grating parameter)

The width of the peaks (FWHM) depends on the number *p* of illuminated slits **FWHM~1/p** 

The **envelope** of the peaks determines the **width** *A* of one slit. **FWHM~1/A** 



#### STRUCTURE RESOLUTION IN RECIPROCAL SPACE







Envelope->

Information about the atomic arrangement inside the unit cell.



#### COMPLEX MOLECULE: INSULIN





#### **DIFFRACTION AND RECIPROCAL SPACE**



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#### FOURIER TRANSFORM: USEFUL RELATIONS

$$I = <|\sum_{j=1}^{N} \hat{A}_{j} e^{i \left(\mathbf{k_{f}} - \mathbf{k_{i}}\right) \cdot \mathbf{r_{j}}} e^{i\omega t} |^{2} >_{t} = |\int \rho\left(\mathbf{r}\right) e^{i\mathbf{Q}\cdot\mathbf{r}} \cdot \mathbf{dr}|^{2}$$

**1. Linearity**: The FT of  $\rho(\vec{r}) = f(\vec{r}) + g(\vec{r})$  is

 $FT\left[f\left(\vec{r}\right) + g\left(\vec{r}\right)\right] = FT\left[f\left(\vec{r}\right)\right] + FT\left[g\left(\vec{r}\right)\right]$ 

2. Convolution: 
$$\rho(\vec{r}) = \int f(\vec{\xi}) g(\vec{r} - \vec{\xi}) d\vec{\xi}$$

# $FT\left[f\left(\vec{r}\right)*g\left(\vec{r}\right)\right] = FT\left[f\left(\vec{r}\right)\right] \bullet FT\left[g\left(\vec{r}\right)\right]$

FT " converts" a convolution in a product and vice versa



#### WE CAN BUILT A SMALL CRYSTAL



Big Crystals-sharp peaks, small crystals broad peaks. Peak intensities depend on the structure factor.

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Miller indices "naming of Bragg peaks": "*(hkl)-peak"* means that the considered netplanes intercept the unit cell axes at positions a/h, b/k, c/l or x/h, y/k, z/l.



Higher indices ->closer net-plane spacings -> higher Q-values.



### **USEFUL RELATIONS IN (RECIPROCAL) Q-SPACE:**

Braggs law: 
$$\sin\theta = \lambda/2d$$
  

$$\int e^{-\frac{4\pi \sin \theta}{\lambda}} \quad \text{with } k = \frac{2\pi}{\lambda}$$

$$\int \frac{1}{\sqrt{2}} \int \frac{1}{$$

#### SIZE BROADENING AND STRAIN BROADENING

Strain may lead to lattice parameter changes or gradients within one crystal.

Assuming a *d*-spacing change *∆d*:

$$Q = \frac{4\pi \sin \theta}{\lambda} = \frac{2\pi}{d} \qquad \frac{\Delta Q}{\Delta d} = -\frac{2\pi}{d^2}$$
Strain broadening  $\Delta Q(\Delta d) = -\frac{\Delta d}{d} \frac{2\pi}{d} = -\frac{\Delta d}{d} Q$  Depends on Q itself
Particle size (D) broadening:  $\Delta Q(D) = \frac{2\pi}{D}$  No Q-dependence
$$(100) \qquad (200) \qquad (300) \qquad (100) \qquad (200) \qquad (300)$$
Size broadening Size broadening for the provided of the pro

#### **DETERMINATION OF LATTICE PARAMETERS**

$$Q = \frac{4\pi\sin\theta}{\lambda} = \frac{2\pi}{d}$$

Resolution only limited by well-definition of the wavelength  $\lambda$  and beam divergence.

Typical absolute resolution of 10<sup>-4</sup>-10<sup>-5</sup> possible without too much effort

Simple structure resolution may not require that. But in order to separate different phases or in order to measure small perturbations in perfect crystals (strain) this is important



#### LIMITS OF RECIPROCAL SPACE

Most of diffraction experiments use "big and homogeneous" samples, like Homogeneous ensembles of nanostructures, chemical solutions or 2D "infinite" structures as surfaces, thin films, ...



## **HETEROGENEOUS STRUCTURES (DEVICES)**

Presence of multiple materials on different lengths scales: new strategy required.





#### **DIFFRACTION IMAGING: SCANNING PROBE**

Use of focused beam/ scanning technique.

Resolution limited by beam spot; limits imposed by source size, working distance and optics Sub 100 nm are possible





# STRUCTURED THIN FILM: TYPICAL FOR A DEVICE

 $\circ$  Si\_{0.8}Ge\_{0.2} layer grown on a Si (001) substrate patterned by focused ion beam (FIB) to draw the ESRF logo.



 $\succ$  Thickness fringes from the SiGe thin film (40nm) can be observed.

SiGe layer inside the logo has been damaged during the FIB process.

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#### **QUALITATIVE ANALYSIS**

- **004** SiGe layer (a):
  - Remains crystalline
  - Is damaged during the FIB process

004 SiGe 2.34 2.08 1.82 1.56 60  $\chi$  ( $\mu m$ ) 1.30 1.04 40 0.78 0.52 0.26 outside the logo 10<sup>9</sup> 0.00 inside the logo 10<sup>8</sup> Log(Intensity) (cts/s)  $10^{7}$ 10<sup>6</sup> 10<sup>5</sup> 10<sup>4</sup> 004Si 004Sige 。  $10^{3}$  $10^{2}$ o Bragg peaks should be analyzed in order to shed light on these defects nature... CHAHINE et al. J. Apple Cryst 2014 20 (°

• At the diffuse **004** Si Bragg reflections, the ESRF logo appears (b), (c), (d).

FIB seen by a traditional scanning probe microscopist



# **STRAIN AND ORIENTATION**



 The Bragg peak position in reciprocal space is essential for retrieving all information related to strain and/or tilts in the structure.

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#### **STRAIN MICROSCOPY**

o numerical Gaussian peak fitting to locate the  $Q_x$ ,  $Q_y$  and  $Q_z$  position of the Bragg peak in the corresponding reciprocal dimension.

oThis generates maps of strain and orientation profiles rather than intensity



 $_{\odot}$  The Si layer underneath the SiGe structured logo is slightly strained (<0.0015%)